

PATENT
1691-0177P

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant: FUKUYAMA, Hiroyuki et al Conf.:

Appl. No.: NEW Group:

Filed: September 20, 2002 Examiner:

For: SINGLE CRYSTALLINE ALUMINIUM NITRIDE
FILM, METHOD OF FORMING THE SAME, BASE
SUBSTRATE FOR GROUP III ELEMENT NITRIDE
FILM, LIGHT EMITTING DEVICE AND SURFACE
ACOUSTIC WAVE DEVICE

COPY

L E T T E R

Assistant Commissioner for Patents
Washington, DC 20231

September 20, 2002

Sir:

Under the provisions of 35 U.S.C. § 119 and 37 C.F.R. § 1.55(a), the applicant(s) hereby claim(s) the right of priority based on the following application(s):

<u>Country</u>	<u>Application No.</u>	<u>Filed</u>
JAPAN	2002-070229	March 14, 2002

A certified copy of the above-noted application(s) is (are) attached hereto.

If necessary, the Commissioner is hereby authorized in this, concurrent, and future replies, to charge payment or credit any overpayment to Deposit Account No. 02-2448 for any additional fee required under 37 C.F.R. §§ 1.16 or 1.17; particularly, extension of time fees.

Respectfully submitted,

BIRCH, STEWART, KOLASCH & BIRCH, LLP

By _____
Marc S. Weiner, #32,181

P.O. Box 747
Falls Church, VA 22040-0747
(703) 205-8000

MSW/jaf
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日本特許庁

JAPAN PATENT OFFICE

(703) 225-5000

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別紙添付の書類に記載されている事項は下記の出願書類に記載されている事項と同一であることを証明する。

This is to certify that the annexed is a true copy of the following application as filed with this Office

出願年月日

Date of Application:

2002年 3月14日

出願番号

Application Number:

特願2002-070229

ST.10/C]:

[JP2002-070229]

出願人

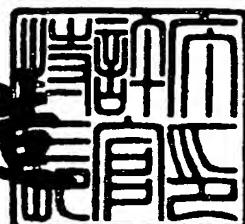
Applicant(s):

財団法人 理工学振興会

2002年 6月 4日

特許庁長官
Commissioner,
Japan Patent Office

及川耕造



出証番号 出証特2002-3044129

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